



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Yasuo FUKUDA et al.

Group Art Unit : 1792

Appln. No. : 10/596,280

Examiner : RAO, G NAGESH

Filed : June 8, 2006

Confirmation No. : 4880

For : EPITAXIAL WAFER AND METHOD FOR PRODUCING SAME

**FIRST SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
U.S. Patent and Trademark Office  
Customer Service Window, Mail Stop Amendment  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314

Sir:

In accordance with the duty of disclosure under 37 C.F.R. §§ 1.56, 1.97, and 1.98, Applicants hereby bring the following information to the attention of the Office, which includes information cited and discussed in the specification, and the Japanese Office Action issued in connection with counterpart International Application No. PCT/JP04/018512. A copy of the Japanese Office Action issued September 5, 2008 is enclosed along with an English language translation. The Examiner is invited to review these materials to inspect the relevance indicated during international examination with respect to the documents cited therein.

The documents are listed below.

- 1) Japanese Patent Publication No. 11-16844, published January 22, 1999; accompanied by an English language abstract (provided by ep.esp@cenet.com) ;
- 2) Japanese Patent Publication No. 11-111661, published April 23, 1999; accompanied by an English language abstract (provided by ep.esp@cenet.com) ;

- 3) Japanese Patent Publication No. 2000-288490, published October 17, 2000;  
accompanied by an English language abstract (provided by ep.esp@cenet.com);
- 4) Japanese Patent Publication No. 2003-1199, published January 7, 2003; accompanied by  
an English language abstract (provided by ep.esp@cenet.com);
- 5) United States Patent No. 6,942,737, issued September 13, 2005 and entitled "Substrate  
Cleaning Apparatus and Method"; Applicants note that this document is an English  
language family member of Japanese Patent Publication No. 2003-1199 as referenced in  
(4) of this Supplemental Information Disclosure Statement;
- 6) Japanese Patent Publication No. 08-078326, published March 22, 1996; accompanied by  
an English language abstract (provided by Patent Abstracts of Japan);
- 7) Japanese Patent Application No. H2003-182615, published July 3, 2003; accompanied by  
an English language abstract (provided by ep.esp@cenet.com)

Copies of the above-noted documents, except for U.S. Patents and U.S. Patent  
Application Publications, are enclosed together with a duly completed Form PTO-1449. The  
Examiner is accordingly requested to consider each of these documents, and to make them of  
record in this application by initialing in the appropriate spaces on the Form PTO-1449.  
Applicant respectfully requests that the Examiner include a copy of the initialed Form PTO-1449  
with the next communication from the U.S. Patent and Trademark Office.


Further to the 37 C.F.R § 1.98, copies of the U.S. patents and U.S. published patent  
applications are not enclosed herewith. However, if any copies are needed, the Examiner is  
respectfully requested to contact the undersigned.

Applicant notes that an Office Action on the merits has not issued in the present  
application, and thus no fee is believed necessary to ensure consideration of the submitted

material. However, if an Office Action on the merits has issued and is crossing this statement in the mail, the undersigned hereby authorizes the Commissioner to charge any fee necessary for the consideration of this statement, including any payment under 37 C.F.R. §1.17 (p) to Deposit Account No. 19-0089.

Should there be any questions, the Examiner is invited to contact the undersigned at the below listed telephone number.

Respectfully submitted,  
Yasuo FUKUDA et al.



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October 17, 2008  
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